



Applicants: Wiesmann, et al.
Serial No.: 10/622,843
Filed: July 18, 2003
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PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: Wiesmann, et al.

Serial No.: 10/622,843

Group Art Unit: 1763

Filed: July 18, 2003

Confirmation No. 4758

For: FLUORINATED PRECURSORS OF SUPERCONDUCTING
CERAMICS, AND METHODS OF MAKING THE SAME

Mail Stop DD
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

INFORMATION DISCLOSURE STATEMENT

Sir:

In order to fulfill the requirements of candor and good faith set forth in 37 C.F.R.

§ 1.56, Applicants submit herewith the following disclosure in accordance with the provisions of
37 C.F.R. § 1.97 and § 1.98.

I. UNITED STATES PATENTS

PATENT NUMBER

ISSUE DATE

PATENTEE

5,231,074

July 27, 1993

Cima et al.

CERTIFICATE OF MAILING (37 CFR 1.8a)

I hereby certify that this paper (along with any papers referred to as being attached or enclosed) is being deposited with the United States Postal Service on the date shown below with sufficient postage as first class mail in an envelope addressed to: Mail Stop DD, Commissioner of Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

11/20/03
Date

Maria Facella
Maria Facella, Office of Intellectual Property and Sponsored Research

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II. OTHER DOCUMENTS

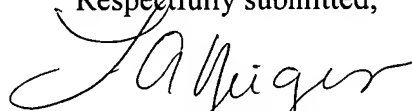
1. **Author:** Chan et al.; **Title:** "Effect of the Post-Deposition Processing Ambient on the Preparation of Superconducting $\text{YBa}_2\text{Cu}_3\text{O}_{7-x}$ Coevaporated Thin Films Using a BaF_2 Source;" **Publication:** *Appl. Phys. Lett.* 53(15): 1443-1445; **Date of Publication:** October 1988.
2. **Author:** Solovyov et al.; **Title:** "*Ex-situ* Post-deposition Processing for Large Area $\text{YBa}_2\text{Cu}_3\text{O}_7$ Films and Coated Tapes;" **Publication:** *IEEE Transactions on Applied Superconductivity* 11(1):2939-2942; **Date of Publication:** March 2001.
3. **Author:** Solovyov et al.; **Title:** "Thick $\text{YBa}_2\text{Cu}_3\text{O}_7$ Films by Post Annealing of the Precursor by High Rate E-beam Deposition on SrTiO_3 Substrates;" *Physica C*. 309: 269-274; **Date of Publication:** December 1998.
4. **Author:** Solovyov et al.; **Title:** "High Rate Deposition of 5 Micron Thick $\text{YBa}_2\text{Cu}_3\text{O}_7$ Films using the BaF_2 Ex-Situ Post Annealing Process;" **Publication:** *IEEE Transactions on Applied Superconductivity* 9(2):1467-1470; **Date of Publication:** June 1999.
5. **Author:** Solovyov et al.; **Title:** "Growth rate limiting mechanisms of $\text{YBa}_2\text{Cu}_3\text{O}_7$ films manufactured by ex situ processing;" **Publication:** *Physica C*. 353:14-22; **Date of Publication:** 2001.
6. U.S. Application Publication No. 2003/0050195.

The above references are also listed on the accompanying Form PTO-1449. The Examiner is respectfully requested to consider these references in their entireties, and to indicate that he or she has done so by initialing the enclosed Form PTO-1449.

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If the Examiner has any questions or comments relating to the present application, he or she is respectfully invited to contact Applicants' attorney at the phone number set forth below.

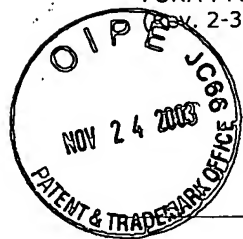
Respectfully submitted,



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 FORM PTO-1449 U.S. DEPARTMENT OF COMMERCE
 (REV. 2-32) PATENT AND TRADEMARK OFFICE

 INFORMATION DISCLOSURE
 STATEMENT BY APPLICANT

(Use several sheets if necessary)

 ATTY. DOCKET NO.
 BSA 03-01

 SERIAL NO.
 10/622,843

 APPLICANT
 Wiesmann, et al.

 CONFIRMATION NO.
 4758

 FILING DATE
 July 18, 2003

 GROUP
 1763

U.S. PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE
	5,231,074	July 27, 1993	Cima et al.			

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

		1. Author: Chan et al.; Title: "Effect of the Post-Deposition Processing Ambient on the Preparation of Superconducting YBa ₂ Cu ₃ O _{7-x} Coevaporated Thin Films Using a BaF ₂ Source;" Publication: <i>Appl. Phys. Lett.</i> 53(15): 1443-1445; Date of Publication: October 1988.
		2. Author: Solovyov et al.; Title: "Ex-situ Post-deposition Processing for Large Area YBa ₂ Cu ₃ O ₇ Films and Coated Tapes;" Publication: <i>IEEE Transactions on Applied Superconductivity</i> 11(1):2939-2942; Date of Publication: March 2001.
		3. Author: Solovyov et al.; Title: "Thick YBa ₂ Cu ₃ O ₇ Films by Post Annealing of the Precursor by High Rate E-beam Deposition on SrTiO ₃ Substrates;" <i>Physica C.</i> 309: 269-274; Date of Publication: December 1998.
		4. Author: Solovyov et al.; Title: "High Rate Deposition of 5 Micron Thick YBa ₂ Cu ₃ O ₇ Films using the BaF ₂ Ex-Situ Post Annealing Process;" Publication: <i>IEEE Transactions on Applied Superconductivity</i> 9(2):1467-1470; Date of Publication: June 1999.
		5. Author: Solovyov et al.; Title: "Growth rate limiting mechanisms of YBa ₂ Cu ₃ O ₇ films manufactured by ex situ processing;" Publication: <i>Physica C.</i> 353:14-22; Date of Publication: 2001.
		6. U.S. Application Publication No. 2003/0050195.

EXAMINER

DATE CONSIDERED

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication with applicant.